

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L13	78	257/E21.224.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 10:05
L12	140	134/33.ccls. and (clean\$4 or etch\$4 or remov\$4 or polish\$4 or grind\$4) near4 (edge or bevel or bead)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 10:05
L11	859	134/33.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 09:44
L10	385	134/9.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 09:44
L3	120	438/694.ccls. and (clean\$4 or etch\$4 or remov\$4 or polish\$4 or grind\$4) near4 (edge or bevel or bead)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 09:44
L9	205	438/748.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 09:16
L4	213	438/747.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 09:02

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S38	15	(US-20030041879-\$ or US-20050087441-\$ or US-20050079713-\$ or US-20010052159-\$ or US-20030116444-\$).did. or (US-5128281-\$ or US-6537416-\$ or US-5176783-\$ or US-6070284-\$ or US-5608943-\$ or US-6797074-\$ or US-6063232-\$ or US-5868857-\$ or US-6550091-\$ or US-6615854-\$).did.	US-PGPUB; USPAT	OR	ON	2006/04/11 08:58
L6	18	("4968375").URPN.	USPAT	OR	ON	2006/04/11 08:54
S20	42	438/694.ccor. and (clean\$4 or etch\$4 or remov\$4 or polish\$4 or grind\$4) near4 (edge or bevel or bead)	US-PGPUB; USPAT	OR	ON	2006/04/11 08:40
S1	3275	(metal or metallic or copper or cu) near5 (edge or bevel or bead) near6 (etch\$4 or remov\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 08:40
L1	3844	438/694.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/11 08:40
S39	584	438/690.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 17:12
S37	19	(metal or metallic or copper or cu) near6 (edge or bevel) near6 (etch\$4 or remov\$4 or clean\$4) and (bead or meniscus or pool or receptacle) near3 (etch or etchant or etching or acid or acidic)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 16:55
S36	11	(electroplat\$4 or electro-plat\$4) near5 (metal or metallic or copper or cu) and (metal or metallic or copper or cu) near5 (edge or bevel) near6 (etch\$4 or remov\$4) and (acid or etchant or etching or etch) near3 (bead\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 16:51
S35	218	edge near bead near (remov\$4) and (cavity or opening or trench or groove or aperture or grooved or contour) near8 (substrate or workpiece or wafer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 16:18

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S34	700	edge near bead near (remov\$4)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 16:18
S33	10	(groove or trench or cavity or opening) near6 (etchant or etching or removing or removal) near6 (bead or surface near tension) same (wafer or substrate or workpiece) near4 (edge or side or bevel or end or outer or outside)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 16:17
S32	340	(groove or trench or cavity or opening) near6 (etchant or etching or removing or removal) near5 (edge or bevel) near6 (wafer or substrate or workpiece)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 16:14
S31	6	("5865984"   "6056869"   "6309981"   "6352623"   "6610190"   "6615854"). PN.	US-PGPUB; USPAT; USOCR	OR	ON	2006/04/10 15:42
S30	444	(substrate or wafer) near2 (edge or bevel) near5 (etch\$4 or remov\$4 or scrub\$4) and (cavity or recess or recessed or opening) near4 (etchant or acid or etching or acidic or solution)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 13:43
S29	3323	(substrate or wafer) near2 (edge or bevel) near3 (etch\$4 or remov\$4 or scrub\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 13:42
S28	117	(substrate or wafer) near5 (edge or bevel or bead) near5 (etch\$4 or remov\$4) and (acid or etchant or etching or fluid) near4 bead	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/10 13:41

# Interference Search

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L14	6	((edge or bevel or circumference or circumferential or end) near4 (wafer or substrate or workpiece) and (etchant or etching or cleaning or cleansing or cleaner or acid) near4 (bead or surface near tension)).clm.	US-PGPUB	OR	ON	2006/04/11 10:16
L16	56	((edge or bevel or circumference or circumferential or end) near4 (wafer or substrate or workpiece) near6 (clean\$4 or removal or removing or etching or etched) near10 (metal or conductive or photoresist or resist)).clm.	US-PGPUB	OR	ON	2006/04/11 10:20
L17	41	((groove or grooved or trench or opening or recess or cavity) near6 (etchant or fluid or acid or cleanser or cleaner or cleaning or etching) near6 (bead or meniscus or surface near tension)).clm.	US-PGPUB	OR	ON	2006/04/11 10:27
L18	10	((groove or grooved or trench or opening or recess or cavity) near6 (etchant or fluid or acid or cleanser or cleaner or cleaning or etching) near6 (bead or meniscus or surface near tension) and (wafer or substrate or workpiece)).clm.	US-PGPUB	OR	ON	2006/04/11 10:27
L19	3	((groove or grooved or trench or opening or recess or cavity) near6 (mated or mating or conforming or holding or conformal or conformed) near4 (edge or circumference or circumferential or curvature or bevel) and (edge or circumference or bevel or outer or end) near3 (clean\$3 or etch\$4)).clm.	US-PGPUB	OR	ON	2006/04/11 10:29
L20	32	((groove or grooved or trench or opening or recess or cavity) and (semiconductor or wafer or workpiece) and (clean\$3 or etch\$4 or remov\$4 near (material or metal or conductive or photoresist or resist)) and (bead or meniscus or tension) and (motion or moving or rotation or rotating or rotated or rpm or sliding)).clm.	US-PGPUB	OR	ON	2006/04/11 10:31